

Nanocomposites and nanomaterials

Effect of Ge content on the formation of Ge nanoclusters in magnetron sputtered GeZrO_x-based structures

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Memory structures with Ge-nanocrystals (NCs) embedded in SiO₂ provide a larger memory window than the devices based on Si-NCs. However, Ge-NCs embedded in “high-k” matrix have attracted attention just recently. In this work, the effect of Ge content on the formation of GeZrO_x solid solution and on thermo-stimulated phase separation followed by the formation of Ge-NCs in ZrO₂ matrix is investigated.

The composite GeZrO_x films as GeZrO_x/ZrO₂ multilayers, fabricated by confocal RF magnetron sputtering of pure Ge and ZrO₂ targets in Ar plasma, were studied by means of spectroscopic ellipsometry, Raman scattering, FTIR and TEM methods versus deposition conditions and annealing treatment.

As-deposited GeZrO_x films were found to be homogeneous whatever Ge content. Thermal treatment stimulated a phase separation and a formation of Ge and ZrO₂ phases. The “start point” of this process depends significantly on Ge content in GeZrO_x films and/or Ge-doped sublayer thickness in multilayer structures. Although the phase separation begins at about 600-700°C, the higher Ge content and/or thicker Ge-doped sublayer result in the lowering of the annealing temperature caused phase separation, nucleation of Ge nanoclusters and their crystallization. Along with this the formation of tetragonal ZrO₂ occurs that offers an achievement of higher dielectric constant. The mechanism of phase separation will be discussed in details and the ways to control the Ge-NCs formation in amorphous ZrO₂ host will be proposed.